# IONEC - Ion Sputter Gun Model IG70-XY-DP with exchangeable apertures





### **Applications**

The IG70-XY-DP lon gun is designed for sample surface cleaning and depth profiling with Auger electron spectroscopy.

Surface treatments with IG70-XY-DP are applicable to a wide range of materials from metals, semiconductors, and oxides, to thin films and 2D layers.

#### **Features:**

- Precision sputtering for sample cleaning and depth profiling
- X-Y ion beam deflection and rastering
- Low operating gas pressure:  $10^{-6} 10^{-7}$  Torr
- Wide range of ion beam diameters and sample distances
- Two long life filaments
- Variety of operating gases: Ar, Noble or Reactive



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# **IONEC - MODEL IG70-XY-DP**

# **Specifications**

### **Precision Power Supply: Model IPS3-D**

	o filament
Ionization Cathode     Tungsten - rhenium filament directly mounted on 70 mm OD CF flange     Beam voltage: 0 - 3.0 kV       Focus voltage: Factor 0.3 - 0.85x     Emission current: 0 - 45 mA	of Beam Energy
Beam Current1.0 μA at 0.25 keV 2.0 μA at 0.5 keVMonitoring:Beam Energy Voltage and Current Emission, total Ion Beam10 μA at 2.0 keV10 keVMonitoring:Beam Energy Voltage and Current Emission, total Ion Beam	nts: Filament Electron
15μA at 3.0 keV Manual Control: of all voltages and Filament curre	ent via rotary dials and
<b>Operating Ar pressure</b> 5.0 x 10 <sup>-6</sup> torr - typical	
Beam Energy 0 - 3.0 keV   On-board 9 adjustable operating programs   Automation: filament forming, constant emissi   diagnostics programs	: outgassing, stand-by on current and
Beam Size From 5 to 25 mm in diameter	
<b>PC Control:</b> Full control of all functions, PC sc	oftware is required
Display: Vacuum fluorescent display	
Gas Input Direct gas input to ion source via leak valve	
Mounting 23/" (70 mm) OD CE flange	e protection
Input: 100/110 V AC 50/60 Hz or 220/24	40 V AC 50 Hz
Bakeability   Under vacuum - 250°C max.   Size:   19" Rack mount box with 3U (5.25 and 17.5" (440 mm) in depth. 12 k	5", 133mm) in height a in weight

# **Ordering Guide**

IG70-XY-DP	lon sputtering gun with direct gas inlet, X-Y deflection plates, differential pumping, adjustable beam size, and CF 2 ¾" (70 mm) OD mounting flange
IPS3-D	Digital power supply with voltage range 0 – 3.0 $kV$
LV-UHV	UHV Precision Gas Leak Valve



Vacuum Microengineering Inc.